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PROCEEDINGS OF SPIE

Scanning Microscopies 2011: Advanced Microscopy Technologies for Defense, Homeland Security, Forensic, Life, Environmental, and Industrial Sciences

**Michael T. Postek
Dale E. Newbury
S. Frank Platek
David C. Joy
Tim K. Mangel**
Editors

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Contents

vii	<i>Conference Committee</i>
xi	<i>Introduction</i>

KEYNOTE SESSION

8036 02	Is scanning electron microscopy/energy dispersive x-ray spectroscopy (SEM/EDS) quantitative? Effect of specimen shape (Keynote Paper) [8036-01] D. E. Newbury, N. W. M. Ritchie, National Institute of Standards and Technology (United States)

FORENSICS

8036 04	Analysis of particles produced during airbag deployment by scanning electron microscopy with energy dispersive x-ray spectroscopy and their deposition on surrounding surfaces: a mid-research summary [8036-18] J. M. Wyatt, U.S. Army Criminal Investigation Lab. (United States)
8036 05	Probative value of gunshot residue on victims of shootings and comparison of gunshot residue results with modern technology versus older testing of samples [8036-04] R. S. White, West Virginia State Police, Retired (United States); W. J. Mershon, Tescan USA Inc. (United States)
8036 06	Scientific working group on gunshot residue (SWGSR): a progress report [8036-05] M. A. Trimpe, Hamilton County Coroner's Lab. (United States)
8036 07	Characterization and source identification of fugitive dusts by light and electron microscopy [8036-06] R. S. Brown, MVA Scientific Consultants (United States)
8036 08	Application possibilities of several modern methods of microscopy and microanalysis in forensic science field [8036-07] M. Kotrlý, I. Turková, Institute of Criminalistics Prague (Czech Republic)

ADVANCEMENTS IN SCANNING ELECTRON MICROSCOPY

8036 0D	Advanced image composition with intra-frame drift correction [8036-12] P. Cizmar, A. E. Vladár, M. T. Postek, National Institute of Standards and Technology (United States)
8036 0E	The characterization of nanoparticles using analytical electron microscopy [8036-13] W. B. Hill, MVA Scientific Consultants (United States)

- 8036 OF **Transmission electron microscopy of electrospun GaN nanofibers** [8036-14]
J. L. Robles-García, A. Meléndez, Univ. of Puerto Rico at Humacao (United States); D. Yates, J. J. Santiago-Avilés, Univ. of Pennsylvania (United States); I. Ramos, Univ. of Puerto Rico at Humacao (United States); E. M. Campo, Univ. of Pennsylvania (United States)
- 8036 OG **Study of LCE nanocomposites through electron microscopy** [8036-15]
N. Torras, J. Jobet, Instituto de Microelectrónica de Barcelona (Spain); J. E. Marshall, Univ. of Cambridge (United Kingdom); K. Zinoviev, Ctr. Instituto de Microelectrónica de Barcelona (Spain); D. Yates, L. Rotkina, Univ. of Pennsylvania (United States); J. Esteve, Instituto de Microelectrónica de Barcelona (Spain); E. M. Terentjev, Univ. of Cambridge (United Kingdom); E. M. Campo, Univ. of Pennsylvania (United States)
- 8036 OH **Morphological classification and microanalysis of tire tread particles worn by abrasion or corrosion** [8036-16]
G. F. Crosta, Univ. degli Studi di Milano-Bicocca (Italy)
- 8036 OI **Nanodispersion, nonlinear image filtering, and materials classification** [8036-17]
G. F. Crosta, Univ. degli Studi di Milano-Bicocca (Italy); J. S. Lee, Univ. of Massachusetts, Lowell (United States)

ADVANCEMENTS IN HELIUM ION MICROSCOPY

- 8036 OK **Investigation of cellular interactions of nanoparticles by helium ion microscopy** [8036-20]
B. W. Arey, V. Shutthanandan, Y. Xie, A. Tolic, N. Williams, G. Orr, Pacific Northwest National Lab. (United States)
- 8036 OM **Creating nanohole arrays with the helium ion microscope** [8036-22]
M. Ananth, L. Stern, D. Ferranti, C. Huynh, J. Notte, L. Scipioni, C. Sanford, B. Thompson, Carl Zeiss NTS, LLC (United States)
- 8036 OO **Secondary electron emission spectra and energy selective imaging in helium ion microscope** [8036-24]
Yu. Petrov, O. Vyvenko, St. Petersburg State Univ. (Russian Federation)

ADVANCES IN SCANNED PROBE MICROSCOPIES I

- 8036 OP **A metrological scanning probe microscope based on a quartz tuning fork detector** [8036-25]
B. Babic, C. H. Freund, M. Lawn, J. R. Miles, J. Herrmann, National Measurement Institute (Australia)
- 8036 OQ **Measurement strategies and uncertainty estimations for pitch and step height calibrations by metrological AFM** [8036-26]
V. Korpelainen, J. Seppä, A. Lassila, Ctr. for metrology and accreditation (Finland)
- 8036 OR **Study of a large range metrological atomic force microscope applied for calibration of a vertical PZT stage** [8036-27]
S. H. Wang, S. L. Tan, G. Xu, A*STAR National Metrology Ctr. (Singapore)

- 8036 0S **Traceable calibration of a critical dimension atomic force microscope** [8036-28]
R. Dixon, N. G. Orji, C. D. McGray, J. Geist, National Institute of Standards and Technology (United States)

ADVANCES IN SCANNED PROBE MICROSCOPIES II

- 8036 0T **Particle number density gradient samples for nanoparticle metrology with atomic force microscopy** [8036-29]
M. A. Lawn, National Measurement Institute (Australia); R. V. Goreham, Univ. of South Australia (Australia); J. Herrmann, Å. K. Jämting, National Measurement Institute (Australia)
- 8036 0U **Development of photomask linewidth measurement and calibration using AFM and SEM in NMIJ** [8036-30]
K. Sugawara, O. Sato, I. Misumi, S. Gonda, M. Lu, National Metrology Institute of Japan (Japan)
- 8036 0V **New developments at PTB in 3D-AFM with tapping and torsion AFM mode and vector approach probing strategy** [8036-31]
G. Dai, W. Häßler-Grohne, D. Hüser, H. Wolff, J. Flügge, H. Bosse, Physikalisch-Technische Bundesanstalt (Germany)

ADVANCES IN OPTICAL MICROSCOPY

- 8036 10 **Through-focus scanning optical microscopy** [8036-36]
R. Attota, R. G. Dixon, A. E. Vladár, National Institute of Standards and Technology (United States)
- 8036 12 **Dispersion free all reflective confocal microscope objective** [8036-38]
W. J. Walecki, Sunrise Optical LLC (United States); M. Scaggs, Neoteric Concepts, LLC (United States); P. S. Walecki, F. Szondy, Sunrise Optical LLC (United States)
- 8036 13 **Use of fluorescence and scanning electron microscopy as tools in teaching biology** [8036-40]
N. Ghosh, West Texas A&M Univ. (United States); J. Silva, A. Vazquez, Eastfield College (United States); A. B. Das, Orissa Univ. of Agriculture & Technology (India); D. W. Smith, Univ. of North Texas (United States)

PARTICLE BEAM INTERACTION WORKSHOP

- 8036 15 **3D-measurement using a scanning electron microscope with four Everhart-Thornley detectors** [8036-42]
T. Vynnyk, R. Scheuer, E. Reithmeier, Leibniz Univ. Hannover (Germany)

Author Index

Conference Committee

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- 1   Keynote Session
     Michael T. Postek, National Institute of Standards and Technology
     (United States)
     Dale E. Newbury, National Institute of Standards and Technology
     (United States)
     S. Frank Platek, U.S. Food and Drug Administration (United States)
- 2   Forensics
     S. Frank Platek, U.S. Food and Drug Administration (United States)
- 3   Advancements in Scanning Electron Microscopy I
     Eva M. Campo, University of Pennsylvania (United States)
     Lucille A. Giannuzzi, L.A. Giannuzzi & Associates LLC (United States)
- 4   Advancements in Scanning Electron Microscopy II
     Lucille A. Giannuzzi, L.A. Giannuzzi & Associates LLC (United States)
     Eva M. Campo, University of Pennsylvania (United States)
- 5   Advancements in Helium Ion Microscopy
     András E. Vladár, National Institute of Standards and Technology
     (United States)
     Michael T. Postek, National Institute of Standards and Technology
     (United States)
- 6   Advances in Scanned Probe Microscopies I
     Ronald G. Dixon, National Institute of Standards and Technology
     (United States)
     Ndubuisi G. Orji, National Institute of Standards and Technology
     (United States)
- 7   Advances in Scanned Probe Microscopies II
     Ronald G. Dixon, National Institute of Standards and Technology
     (United States)
     Ndubuisi G. Orji, National Institute of Standards and Technology
     (United States)
- 8   Advances in Optical Microscopy
     Ravikiran Attota, National Institute of Standards and Technology
     (United States)
     Tim K. Maugel, University of Maryland, College Park (United States)

- 9 Particle Beam Interaction Workshop
John S. Villarrubia, National Institute of Standards and Technology
(United States)
András E. Vladár, National Institute of Standards and Technology
(United States)

Introduction

The Scanning Microscopies 2011: Advanced Microscopy Technologies for Defense, Homeland Security, Forensic, Life, Environmental, and Industrial Sciences (SCANNING) meeting brought microscopists from all aspects of scanning microscopies (from scanned optics and probes to scanned particle beams) together in a single forum to discuss current research and new advancements in the field. This year, the SCANNING 2011 meeting joined the SPIE Defense, Security, and Sensing 2011 (DSS 2011) conference in Orlando, Florida. On the surface this does not seem intuitive but the past SCANNING meetings have had a large forensics following which is strongly supportive of both defense and homeland security. Scanned microscopies are also key investigative and research tools in all three of the topics encompassed by the meeting, as evidenced by attending other presentations of DSS 2011. It became clear that scanning microscopies are used across the gamut of topics covered by this overall symposium and merging SCANNING with this symposium was an appropriate move for the future.

Spring conferences on scanning microscopy have a history going back to 1967 with the "IITRI Scanning Electron Microscopy" series started by Dr. Om Johari. Following Dr. Johari's retirement, the SCANNING series of conferences organized by Ms. Tony Bourgholtzer of the Foundation for Advances in Medicine and Science (FAMS), continued this tradition. Early in 2007, FAMS decided to discontinue sponsorship of future SCANNING meetings. Since the FAMS announcement, a substantial amount of work went on in the background to find a solution to keep the meeting alive. SCANNING 2009 was ultimately organized through SPIE (the International Society for Optical Engineering) and as a bridge to that meeting, a highly successful spring scanning microscopy meeting was held at the National Institute of Standards and Technology (NIST) in Gaithersburg, Maryland in 2008. Subsequently, SCANNING 2009 and SCANNING 2010 were held in Monterey, California but it became clear that it was advantageous for SCANNING 2011 to ally itself with a larger meeting. Thus, it became a part of the SPIE Defense, Security, and Sensing 2011 conference in Orlando, Florida. In 2012 the SPIE Defense, Security, and Sensing conference will move to Baltimore, Maryland where the scanning microscopies research and user base is quite large. We are highly optimistic about this change in venue.

The SCANNING 2011 conference was quite successful. Sessions encompassed papers covering forensics applications, scanning electron microscopy, helium ion microscopy; scanned probe microscopy, scanned optical microscopy and particle beam microscopy. In addition, the Particle Beam Interaction Workshop

was held for the 17th year. This workshop has been responsible for the rapid development of accurate models for particle beam, microanalysis, and scanned probe microscopy. The Scanning Microscopy in Forensic Science Short Course was also offered for the 16th year and has proven to be valuable in the training of forensic scientists across the world.

Michael T. Postek
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Tim K. Maugel